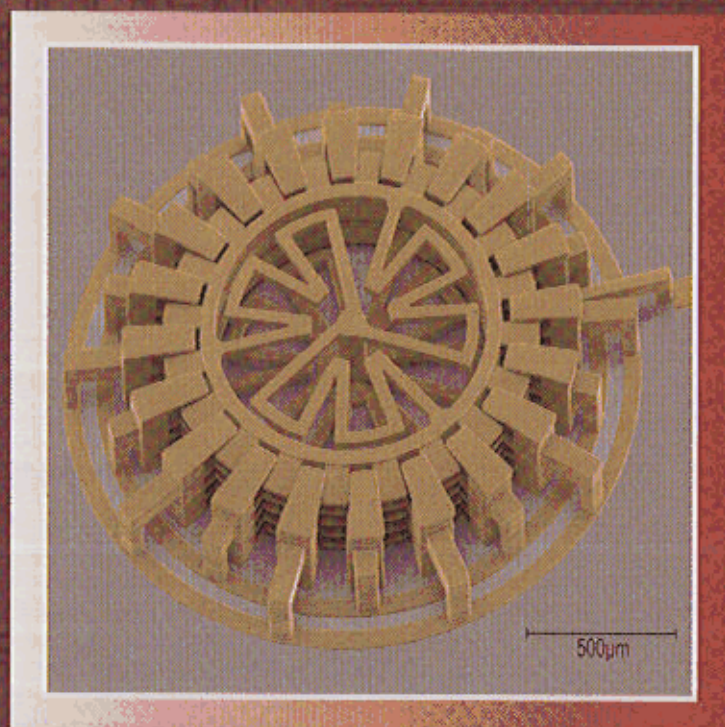


The MEMS Handbook

Second Edition

MEMS

Applications



Edited by
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